

REMARKS

Applicant respectfully requests consideration of the subject application as amended herein. This Amendment is submitted in response to a Final Office Action mailed on March 18, 2004. Claims 1-12 are rejected. Claim 1 has been amended. Claims 13-24 have been withdrawn. No new matter has been added.

35 U.S.C. § 112, second paragraph

The Examiner rejected claims 1-12 under 35 U.S.C. § 112, second paragraph, as being indefinite for failing to particularly point out and distinctly claim the subject matter which applicant regards as the invention. Claim 1 has been amended. Applicant submits that the amendment does not add new matter.

As can be seen, claim 1-12 now refer to bringing the terminals on the dies into contact with contacts connected to an electric tester... As stated in the disclosure at page 12 [0049] for example, the test chuck 32 can then be moved in x-, y-, and z-directions so that each one of the contacts 38 is brought into contact with a respective set of terminals on one of the substrates 56, followed by x-, y-, and z-movements of the test chuck 32 so that each one of the contacts 38 contacts a respective terminal on the other substrate, followed then by the third substrate.

35 U.S.C. § 102(b)

The Examiner rejected claim 1 under 35 U.S.C. § 102(b), second paragraph, as being anticipated by Obigane.

Applicant respectfully disagrees. Obigane pertains to a testing apparatus that only test one wafer at a time. As can be seen from column 4, line 55 to column 5, line 8, when the test is finished, the wafer is unloaded from the chuck 21 to the cassette 15 on the first

elevator 31. When the wafer W is returned into the cassette 15 on the first elevator 31 in this manner, the next wafer W is taken out from the same cassette 15 and then tested in the same manner as described above. When all of the wafers W in the first cassette 15 are successively tested in this manner and their testing is finished, the first elevator 31 is lowered to return the cassette 15 to home position HP. Thus, the Obigane testing apparatus is capable of only testing one wafer at a time.

On the other hand, Applicant's invention pertains to a system having an ability to perform testing for multiple substrates.

Thus, Applicant submits that Obigane does not anticipate claims 1-12.

Also, Applicant submits that Mizumura does not anticipate claims 1-12 or make obvious claims 1-12. Mizumura pertains to a probing apparatus includes moving means 4 for receiving a card holder 2 accommodating a probe card 1, moving the card holder 2 into a position just below a pin socket 3 to which the probe card 1 is attached, and lifting the card holder 2, and attaching means 5 for attaching the probe card 1 to the pogo pin socket 3. (See Abstract). At the very least, Mizumura does not pertain to a system having an ability to perform testing for multiple substrates as claims 1-12. Thus, Mizumura does not anticipate claims 1-12 or make obvious claims 1-12.

If the Examiner finds any remaining impediment to the prompt allowance of these claims that could be clarified with a telephone conference, the Examiner is respectfully to contact Mimi Diemmy Dao at (408) 720-8300.

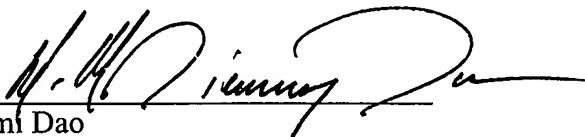
Deposit Account Authorization

Authorization is hereby given to charge our Deposit Account No. 02-2666 for any charges that may be due.

Respectfully submitted,

BLAKELY, SOKOLOFF, TAYLOR & ZAFMAN LLP

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